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Čiste sobe in podobna nadzorovana okolja - 9. del: Ocenjevanje čistosti površine na osnovi koncentracije delcev (ISO/FDIS 14644-9:2021)

Cleanrooms and associated controlled environments - Part 9: Assessment of surface cleanliness for particle concentration (ISO/FDIS 14644-9:2021)

Reinräume und zugehörige Reinraumbereiche - Teil 9: Klassifizierung der partikulären Oberflächenreinheit (ISO/FDIS 14644-9:2021)

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Cleanrooms and associated controlled environments —

Part 9:

Assessment of surface cleanliness for particle concentration

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Foreword

ISO (the International Organization for Standardization) is a worldwide federation of national standards bodies (ISO member bodies). The work of preparing International Standards is normally carried out through ISO technical committees. Each member body interested in a subject for which a technical committee has been established has the right to be represented on that committee. International organizations, governmental and non-governmental, in liaison with ISO, also take part in the work. ISO collaborates closely with the International Electrotechnical Commission (IEC) on all matters of electrotechnical standardization.

The procedures used to develop this document and those intended for its further maintenance are described in the ISO/IEC Directives, Part 1. In particular, the different approval criteria needed for the different types of ISO documents should be noted. This document was drafted in accordance with the editorial rules of the ISO/IEC Directives, Part 2 (see www.iso.org/directives).

Attention is drawn to the possibility that some of the elements of this document may be the subject of patent rights. ISO shall not be held responsible for identifying any or all such patent rights. Details of any patent rights identified during the development of the document will be in the Introduction and/or on the ISO list of patent declarations received (see www.iso.org/patents).

Any trade name used in this document is information given for the convenience of users and does not constitute an endorsement.

For an explanation of the voluntary nature of standards, the meaning of ISO specific terms and expressions related to conformity assessment, as well as information about ISO's adherence to the World Trade Organization (WTO) principles in the Technical Barriers to Trade (TBT), see www.iso.org/iso/foreword.html.

This document was prepared by Technical Committee ISO/TC 209, *Cleanrooms and associated controlled environments*, in collaboration with the European Committee for Standardization (CEN) Technical

environments, in collaboration with the European Committee for Standardization (CEN) Technical Committee CEN/TC 243, *Cleanroom technology*NinSacdordahce2with the Agreement on technical cooperation between ISO and CEN (Vienna Agreement).og/standards/sist/090e027d-

This second edition cancels and replaces the first edition (ISO 14644-9:2012), of which it constitutes a minor revision. The changes are as follows: 2022

- "Class" (classification, classified) has been changed to grade or assessment where appropriate;
- ISO 14644-6 has been removed from the opening text of <u>Clause 3</u> and, as a result, <u>Clause 2</u>;
- entry 3.8 removed from <u>Clause 3</u>;
- minor editorial changes.

A list of all parts in the ISO 14644 series can be found on the ISO website.

Any feedback or questions on this document should be directed to the user's national standards body. A complete listing of these bodies can be found at <u>www.iso.org/members.html</u>.

Introduction

Cleanrooms and associated controlled environments provide for the control of contamination to levels appropriate for accomplishing contamination-sensitive activities. Products and processes that benefit from the control of contamination include those in such industries as aerospace, microelectronics, optics, nuclear and life sciences (pharmaceuticals, medical devices, food, healthcare).

ISO 14644-1 to ISO 14644-8, ISO 14698-1 and ISO 14698-2 deal exclusively with airborne particle and chemical contamination. Many factors, besides the assessment of surface cleanliness, should be considered in the design, specification, operation and control of cleanrooms and other controlled environments. These factors are covered in some detail in other parts of ISO 14644 and ISO 14698.

This document provides an analytical process for the determination and designation of surface cleanliness levels based on particle concentration. This document also lists some methods of testing, as well as procedure(s) for determining the concentration of particles on surfaces.

Where regulatory agencies impose supplementary guidelines or restrictions, appropriate adaptations of the testing procedures might be required.

NOTE When assessment of surface cleanliness by particle concentration (SCP) at critical control point(s) is used as an additional cleanliness attribute to classification of air cleanliness by airborne particle concentration in accordance with ISO 14644-1, then the space can be described as a cleanroom or clean-zone. If SCP is used alone, then the space is described as a controlled zone to the space of the space can be described as a cleanroom or clean-zone. If SCP is used alone, then the space is described as a controlled zone.

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Cleanrooms and associated controlled environments -

Part 9: Assessment of surface cleanliness for particle concentration

1 Scope

This document establishes a procedure for the assessment of particle cleanliness levels on solid surfaces in cleanrooms and associated controlled environment applications. Recommendations on testing and measuring methods, as well as information about surface characteristics, are given in <u>Annexes A</u> to <u>D</u>.

This document applies to all solid surfaces in cleanrooms and associated controlled environments, such as walls, ceilings, floors, working environments, tools, equipment and products. The procedure for the assessment of surface cleanliness by particle concentration (SCP) is limited to particles of between 0,05 μ m and 500 μ m.

The following issues are not considered in this document:

- requirements for the cleanliness and suitability of surfaces for specific processes;
- procedures for the cleaning of surfaces:
- material characteristics;
- references to interactive bonding forces for generation2processes that are usually time-dependent and process-dependent;tandards.iteh.ai/catalog/standards/sist/090e027d-
- selection and use of statistical methods for assessment and testing;

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 other characteristics of particles, such as electrostatic charge, ionic charges and microbiological state.

2 Normative references

There are no normative references in this document.

3 Terms and definitions

For the purposes of this document, the following terms and definitions apply.

ISO and IEC maintain terminology databases for use in standardization at the following addresses:

- ISO Online browsing platform: available at https://www.iso.org/obp
- IEC Electropedia: available at <u>https://www.electropedia.org/</u>

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3.1

descriptor for specific particle size ranges

differential descriptor that expresses surface cleanliness by particle concentration (SCP) level within specific particle size ranges

Note 1 to entry: The descriptor may be applied to particle size ranges of special interest or those particle size ranges that are outside the range of the grading system and specified independently or as a supplement to the SCP levels.

3.2

direct measurement method

assessment of the contamination without any intermediate steps

3.3

indirect measurement method

assessment of the contamination with intermediate steps

3.4

solid surface

boundary between the solid and a second phase

3.5

surface particle

solid and/or liquid matter adhered and discretely distributed on a surface of interest, excluding filmlike matter that covers the whole surface

Note 1 to entry: Surface particles are adhered via chemical and /or physical interactions.

surface cleanliness by particle concentration ards.iteh.ai)

SCP

condition of a surface with respect to its particle concentration 9.2022

Note 1 to entry: The surface the animess depends upon material and idesign characteristics, stress loads (complexity of loads acting on a surface) and prevailing environmental conditions, along with other factors.

3.7

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surface cleanliness by particle concentration level **SCP** rating

grading number stating the maximum allowable surface concentration, in particles per square metre, for a considered size of particles [surface cleanliness by particle concentration (SCP) grades 1 to 8], where level 1 represents the cleanest level

3.8

surface particle concentration

number of individual particles per unit of surface area under consideration

Abbreviated terms 4

For the purposes of this document, the following abbreviated terms apply.

- AFM atomic force microscopy
- CNC condensation nucleus counter
- EDX energy dispersive X-ray spectroscopy
- **ESCA** electron spectroscopy for chemical analysis
- ESD electrostatic discharge

- IR infrared (absorption spectroscopy)
- OPC optical particle counter
- PET polyethylene terephthalate
- SCP surface cleanliness by particle concentration
- SEM scanning electron microscopy
- UV ultraviolet (spectroscopy)
- WDX wavelength-dispersive X-ray spectroscopy

5 The surface cleanliness level assessment system

5.1 ISO-SCP grading level format

The degree of SCP in a cleanroom or associated controlled environment shall be designated by a cleanliness level grading number, N, specifying the maximum total particle concentration on surfaces permitted for a considered particle size. N shall be determined from Formula (1) with the maximum permitted total particle concentration on the surface, $C_{SCP;D}$, in particles per square metre of surface, for each considered particle size, D:

$$C_{\text{SCP};D} = k \frac{10^{N}}{D} \qquad \begin{array}{c} \text{PREVIEW} \\ \text{(standards.iteh.ai)} \end{array}$$
(1)

where

- $C_{\text{SCP;D}}$ is the maximum permitted total surface concentration, in particles per square metre of surface of particles that are equal to or larger/than the considered particle size; $C_{\text{SCP;D}}$ is rounded to the nearest whole number, using no more than three significant figures;
- *N* is the SCP cleanliness level grading number, which is limited to SCP grade level 1 to SCP grade level 8; the SCP grade level number *N* is qualified by the measured particle diameter *D*, in micrometres;

NOTE \$N\$ refers to the exponent base 10 for the concentration of particles at the reference particle size of 1 $\mu m.$

- *D* is the considered particle size, in micrometres;
- *k* is a constant 1, in micrometres.

NOTE 1 The SCP grade level based on the particle concentration can be a time- and process-dependent value due to the dynamic characteristics of particle generation and transportation.

NOTE 2 Due to the complexity of statistical evaluations and readily available additional references, the selection and use of statistical methods for testing are not described in this document.

The concentration $C_{\text{SCP};D}$, as derived from Formula (1), shall serve as the definitive value. Table 1 presents selected SCP grading levels and corresponding maximum cumulative permitted total surface concentrations for considered particle sizes.

Figure 1 provides a representation of the selected surface particle grade levels in graphical form.

Table 1 — Selected SCP grading levels for cleanrooms and associated controlled environments

Units in particles per square metre

SCP level	Particle size									
SCP level	≥ 0,05 µm	≥ 0,1 µm	≥ 0,5 µm	≥1µm	≥ 5 µm	≥ 10 µm	≥ 50 µm	≥ 100 µm	≥ 500 µm	
SCP level 1	(200)	100	20	(10)						
SCP level 2	(2 000)	1 000	200	100	(20)	(10)				
SCP level 3	(20 000)	10 000	2 000	1 000	(200)	(100)				
SCP level 4	(200 000)	100 000	20 000	10 000	2 000	1 000	(200)	(100)		
SCP level 5		1 000 000	200 000	100 000	20 000	10 000	2 000	1 000	(200)	
SCP level6		(10 000 000)	2 000 000	1 000 000	200 000	100 000	20 000	10 000	2 000	
SCP level 7				10 000 000	2 000 000	1 000 000	200 000	100 000	20 000	
SCP level 8						10 000 000	2 000 000	1 000 000	200 000	

The values in <u>Table 1</u> are concentrations of particles of the related particle size and SCP level per surface area of one square metre (1 m^2) equal to or larger than the considered particle size $(C_{\text{SCP},\text{D}})$.

For figures in parentheses, the corresponding particle sizes should not be used for level determination purposes; select another particle size for more accurate determination.

The minimum area for testing should be statistically representative of the surface under consideration.

NOTE Assessment of the lower SCP levels requires numerous measurements to establish a significant value.

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